

# PROCEEDINGS OF SPIE

## ***Optical Design and Testing VI***

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*Editors*

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# Contents

- vii *Authors*
- ix *Symposium Committees*
- xi *Conference Committee*

---

## **SESSION 1 ILLUMINATION OPTICS**

---

- 9272 02 **Light scattering characterization of optical components: BRDF, BTDF, and scatter losses (Invited Paper) [9272-1]**
- 9272 03 **Extremely small red-green-blue beam combiners for compact projection-type displays (Invited Paper) [9272-2]**
- 9272 04 **UV-LED system to obtain high power density in specific working-plane (Invited Paper) [9272-3]**
- 9272 05 **Design of directional light source for blue phase LCD [9272-4]**
- 9272 06 **Graphene composite anode for flexible polymer light emitting diode (Best Student Paper Award) [9272-5]**
- 9272 07 **Feedback modification strategy for designing a free-form optical surface with given illumination pattern [9272-6]**

---

## **SESSION 2 3D IMAGING AND DISPLAY: JOINT SESSION WITH CONFERENCES 9271 AND 9272**

---

- 9272 08 **Three-dimensional image formation based on scanning with a floating real image (Invited Paper) [9272-7]**
- 9272 09 **3D goes digital: from stereoscopy to modern 3D imaging techniques (Invited Paper) [9272-8]**

---

## **SESSION 3 MICROSCOPY AND INTERFEROMETRY**

---

- 9272 0A **Imaging microscopy by phase-contrast engine: retardation-modulated differential interference contrast microscope (Invited Paper) [9272-9]**
- 9272 0B **Phase-contrast scanning optical microscopy for biological tissues (Invited Paper) [9272-10]**
- 9272 0C **Integrated phase-shifting digital holography using statistical approach (Invited Paper) [9272-11]**

9272 OD **High-precision three-dimensional coordinate measurement with subwavelength-aperture-fiber point diffraction interferometer** [9272-12]

9272 OE **Freeform metrology based on phase retrieval and computer-generated hologram** [9272-13]

---

**SESSION 4 NOVEL OPTICAL SYSTEM DESIGN**

---

9272 OG **Polarization aberration function for perturbed lithographic lens (Invited Paper)** [9272-15]

9272 OH **Design, simulation and experimental analysis of an anti-stray-light illumination system of fundus camera (Invited Paper)** [9272-16]

---

**SESSION 5 DESIGN AND FABRICATION METHODS**

---

9272 OJ **Effect of higher order aberrations on a radially polarized beam (Invited Paper)** [9272-18]

9272 OK **Nanofabrication with sub-50nm features by imprinting-induced cracks** [9272-19]

9272 OL **A simple method generating first-order optical structure based on particle swarm algorithm** [9272-20]

9272 OM **MTF curve integral calculation method and its application in image quality evaluation** [9272-21]

9272 ON **The investigation of large field of view eyepiece with multilayer diffractive optical element** [9272-22]

---

**SESSION 6 OPTICAL TESTING AND MEASUREMENT**

---

9272 OO **Optical metrology techniques and apparatus for lens assembly (Invited Paper)** [9272-23]

9272 OP **Single camera stereo vision coordinate measurement in parts pose recognition on CMM** [9272-24]

9272 OQ **Inertially stabilized line-of-sight control system using a magnetic bearing with vernier gimbaling capacity** [9272-25]

9272 OR **Design and implementation of high power LED machine vision lighting system** [9272-26]

---

**POSTER SESSION**

---

9272 OS **CFRP variable curvature mirror being capable of generating a large variation of saggitus: prototype design and experimental demonstration** [9272-27]

9272 OU **Design of an ultra-thin dual band infrared system** [9272-29]

- 9272 0W **Design of a dual-band MWIR/LWIR circular unobscured three-mirror optical system with Zernike polynomial surfaces** [9272-32]
- 9272 0X **Design and optimization of optical system for a spectrometer based on VPHT grating** [9272-33]
- 9272 0Y **Optical performance study of duplex Y-branch coupler with different structures** [9272-34]
- 9272 0Z **Design of blue LEDs array with high optical power** [9272-35]
- 9272 10 **Calculation of Mueller matrix for light scattering from randomly rough surface** [9272-36]
- 9272 12 **Design and experimental demonstration of variable curvature mirror having a large saggitus variation** [9272-38]
- 9272 14 **Freeform lens design using a complementary optimization method for uniform illumination with extended LED light sources** [9272-40]
- 9272 16 **Design of vari-focal panoramic annular lenses based on Alvarez surfaces** [9272-43]
- 9272 17 **Effect of environmental temperature on diffraction efficiency for multilayer diffractive optical elements in mid-wave infrared** [9272-44]
- 9272 18 **Correcting the wavefront aberration of membrane mirror based on liquid crystal spatial light modulator** [9272-45]
- 9272 1B **Two-dimension lateral shearing interferometry for microscope objective wavefront metrology** [9272-48]
- 9272 1C **Enhancement of wireless ultraviolet communication system using FEC codes** [9272-49]
- 9272 1D **Distortion control for panoramic annular lens with Q-type aspheres** [9272-50]
- 9272 1E **The experiment to detect equivalent optical path difference in independent double aperture interference light path based on step scanning method** [9272-51]
- 9272 1G **Wavefront reconstruction for image restoration based on generalized ridge estimation** [9272-53]
- 9272 1H **Aberration resilience of azimuthally polarized beam with a helical phase mask** [9272-55]
- 9272 1I **The design of an ultra-thin and multiple channels optical receiving antenna system with freeform lenses** [9272-56]
- 9272 1J **Angular-momentum-dependent splitting of light through metal nanohole** [9272-57]
- 9272 1K **Generation of radially and azimuthally polarized beams with an inner wall waveguide fiber** [9272-58]
- 9272 1L **Lens design based on lens form parameters using Gaussian brackets** [9272-59]
- 9272 1N **Polarization state control using metal nanograting** [9272-61]

- 9272 1O **A microspectrometer based on subwavelength metal nanohole array** [9272-62]
- 9272 1Q **Measurement of radius of curvature of spherical optical surfaces with small curvature and aperture by optical profiler** [9272-64]
- 9272 1R **Design of hard x-ray focusing telescope with a large field-of-view** [9272-65]
- 9272 1S **Enhancement of light absorption in organic solar cells by using plasmonic gratings** [9272-66]
- 9272 1U **Design of solar-blind UV optical system for missile approach warning** [9272-68]
- 9272 1W **A high efficiency LED portable desk lamp based on V-groove cells LGP** [9272-70]
- 9272 1X **The deflection effect of starlight transmission in hypersonic conditions** [9272-71]
- 9272 1Y **Analysis of error propagation in an improved zonal phase-gradient model** [9272-72]
- 9272 1Z **A novel solution for LED wall lamp design and simulation** [9272-73]
- 9272 20 **Smart structures on multiple configuration systems in image sensor** [9272-74]
- 9272 21 **Design of freeform illumination sources with arbitrary polarization for immersion lithography** [9272-75]

## Authors

Numbers in the index correspond to the last two digits of the six-digit citation identifier (CID) article numbering system used in Proceedings of SPIE. The first four digits reflect the volume number. Base 36 numbering is employed for the last two digits and indicates the order of articles within the volume. Numbers start with 00, 01, 02, 03, 04, 05, 06, 07, 08, 09, 0A, 0B...0Z, followed by 10-1Z, 20-2Z, etc.

Alt, Mark, 0O  
Bai, Jian, 16, 1D  
Boruah, Bosanta R., 0J, 1H, 1Y  
Cai, Wentao, 04  
Cen, Zhaofeng, 07  
Chen, Bo, 1G  
Chen, Chi-Feng, 1W  
Chen, Jie-Wen, 05  
Chen, Jin-Jia, 0Y, 14  
Chen, Li, 0P  
Chen, Peng-bo, 0R  
Chen, Shenghao, 1Q, 1R  
Chen, Weimin, 06  
Chen, Xinhua, 18  
Chen, Xin-yang, 1E  
Chen, Xixi, 0D  
Chen, Yu, 1U  
Chen, Yuhao, 07  
Cheng, Dewen, 0H, 1I  
Cheng, Xuemin, 0U, 1L  
Cui, Jun, 1O  
Cui, Qingfeng, 0W, 17  
Davis, Colleen, 0O  
Ding, Jei, 0Y  
Ding, Quanxin, 20  
Ding, Yuanyuan, 1E  
Dong, Yun, 07  
Du, Chunlei, 04, 06, 0K, 1O  
Du, JingLei, 1J, 1N, 1S  
Du, Ke, 0U  
Du, Yunfei, 0S  
Duparré, Angela, 02  
Fan, Changjiang, 0N  
Fan, Xuewu, 0S  
Gaffar, Md., 0J, 1H  
Gao, Xing-yu, 0R  
Gardner, Michael L., 0O  
Ge, Rui, 1Z  
Gou, Jian, 04  
Gu, Huarong, 0E  
Han, Yue, 0O  
Hisaka, Masaki, 0B  
Hong, Weibin, 1Z  
Hu, Dejiao, 1J, 1N, 1S  
Hu, Jing, 1X  
Hu, YiFei, 0U  
Hu, Yuan, 1I  
Huang, Deping, 06  
Huang, Feng-shan, 0P  
Huang, Huijie, 0L  
Huang, Kuang-Lung, 0Y, 14  
Huang, Wei, 0G  
Huang, Yin, 0M  
Huang, Zhen, 0X  
Huo, Furong, 1U  
Ishiwata, Hiroshi, 0A  
Itoh, Masahide, 0A  
Ji, Zheng, 0O  
Jiang, Shu, 10  
Jiang, Yadong, 1B  
Jin, Guofan, 0E  
Kajihara, Kazuki, 0C  
Katsir, Dina, 02  
Katsuyama, Toshio, 03  
Kerwien, N., 09  
Kong, Ming, 0D  
Kuo, Shin-Hong, 1W  
Lee, King-Lien, 05  
Leng, Chongqian, 06  
Li, Jing, 0Z  
Li, Jinmin, 0Z  
Li, Kuangqi, 1Z  
Li, Ming-dong, 0R  
Li, Qing, 1C  
Li, Renyuan, 04  
Li, Xiaotong, 07  
Li, Yanqiu, 21  
Li, Zhancheng, 06  
Li, Zhenhua, 10  
Liang, Pengxiang, 1Z  
Lin, Che-Yen, 05  
Lin, Zhuchong, 0Q  
Liu, Guodong, 0X  
Liu, Hua, 20  
Liu, Ke, 21  
Liu, Kun, 0Q  
Liu, Te-Shu, 0Y  
Liu, Yi, 0E  
Liu, Yu, 1J, 1S  
Liu, Zhihai, 1K  
Liu, Zhixiang, 1B  
Lu, Pengzhi, 0Z  
Luo, Wei, 06  
Luo, Yujie, 16  
Lv, Baobin, 1B  
Lv, Qichao, 0U  
Lv, Xiangbo, 0L  
Ma, Chen, 0H

Ma, Shuang, 1Q, 1R  
 Ma, Shu-jing, 0M  
 Ma, Zhen, 0S  
 Menke, Neimule, 12  
 Miyazaki, Daisuke, 08  
 Mu, Baozhong, 1R  
 Nakao, Akira, 03  
 Ogawa, Kosuke, 03  
 Pang, Zhihai, 0S  
 Pathak, Biswajit, 1Y  
 Piao, Mingxu, 0W, 17  
 Ren, Guorui, 0S, 12  
 Ren, Zhong, 0X  
 Schröder, Sven, 02  
 Shi, Haofei, 06  
 Shiratori, Takaaki, 0C  
 Song, Qiang, 0L  
 Song, Weitao, 1I  
 Song, Yuanyuan, 10  
 Su, Yu, 0S  
 Sun, Xiuhui, 04  
 Takahata, Kohei, 03  
 Tan, Qiaofeng, 0E  
 Tang, Minxue, 18  
 Tang, Zhaoxin, 0G  
 Tsai, Po-Yu, 05  
 Tsujino, Kenta, 03  
 von Finck, Alexander, 02  
 Wang, Chaoyan, 1E  
 Wang, Chuen-Ching, 14  
 Wang, Chun-mei, 0P  
 Wang, Daodang, 0D  
 Wang, Fumin, 0D  
 Wang, Guohong, 0Z  
 Wang, Junxi, 0Z  
 Wang, Shouyu, 10  
 Wang, Shuping, 0O  
 Wang, Te-Yuan, 14  
 Wang, Wei, 0S  
 Wang, Xue-sha, 0P  
 Wang, Yongtian, 0H, 11  
 Wang, Zhanshan, 1Q, 1R  
 Wei, Jingxuan, 0S, 12  
 Wei, Lidong, 2I  
 Wei, Yin, 18  
 Xia, Liangping, 0K, 1O  
 Xiao, Hua-peng, 0R  
 Xiao, Xiao, 1J, 1S  
 Xiao, Ze-xin, 0M  
 Xie, Haizhong, 0Z  
 Xie, Shiwei, 1S  
 Xie, Xiaopeng, 0S, 12  
 Xie, Yongjie, 0S  
 Xing, Tingwen, 1B  
 Xiong, Zhihua, 0X  
 Xu, Chen, 0H  
 Xu, Fuchao, 1B  
 Xu, Mingfei, 0G  
 Xu, Weicai, 0G  
 Xu, Xiangru, 0G  
 Xu, Yangbo, 0D  
 Xue, Bin, 0Z  
 Xue, Liang, 10  
 Yan, Keding, 10  
 Yan, Zhengang, 10  
 Yang, Bin, 18  
 Yang, Bo, 1X  
 Yang, Hua, 0Z  
 Yang, Jun, 06  
 Yang, Shuo, 1C  
 Yang, Yang, 1G  
 Yang, Zheng, 0K, 1O  
 Yao, Yuan, 16  
 Yi, Shengzhen, 1Q  
 Yi, Xiaoyan, 0Z  
 Yin, Lu, 1O  
 Yin, Shaoyun, 04, 0K, 1O  
 Yoshikawa, Nobukazu, 0C  
 Yuan, Xiangyu, 1L  
 Yue, Weirui, 0L  
 Yue, Yang, 1N  
 Zeitner, Uwe, 02  
 Zeng, Fa, 0E  
 Zhai, Yucui, 1S  
 Zhang, Bo, 17  
 Zhang, Chi, 0O  
 Zhang, Fang, 0L  
 Zhang, Feng, 1C  
 Zhang, Lingyun, 1I  
 Zhang, Man, 0K  
 Zhang, Min, 1C  
 Zhang, Xiang, 1C  
 Zhang, Yansong, 1C  
 Zhang, Yongna, 06  
 Zhang, ZhiYou, 1J, 1N, 1S  
 Zhao, Chunzhu, 0W  
 Zhao, Fuli, 1Z  
 Zhao, Hui, 0S, 12  
 Zhao, Jun, 0D  
 Zhao, Yujing, 1K  
 Zheng, Guoxing, 1O  
 Zheng, Liqin, 1U  
 Zheng, Lixin, 1E  
 Zhou, Liwei, 20  
 Zhou, Xiangdong, 1D  
 Zhou, Zhehai, 0E  
 Zhu, Hao, 0W, 17  
 Zhu, Jing, 0L

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